Fig. 1

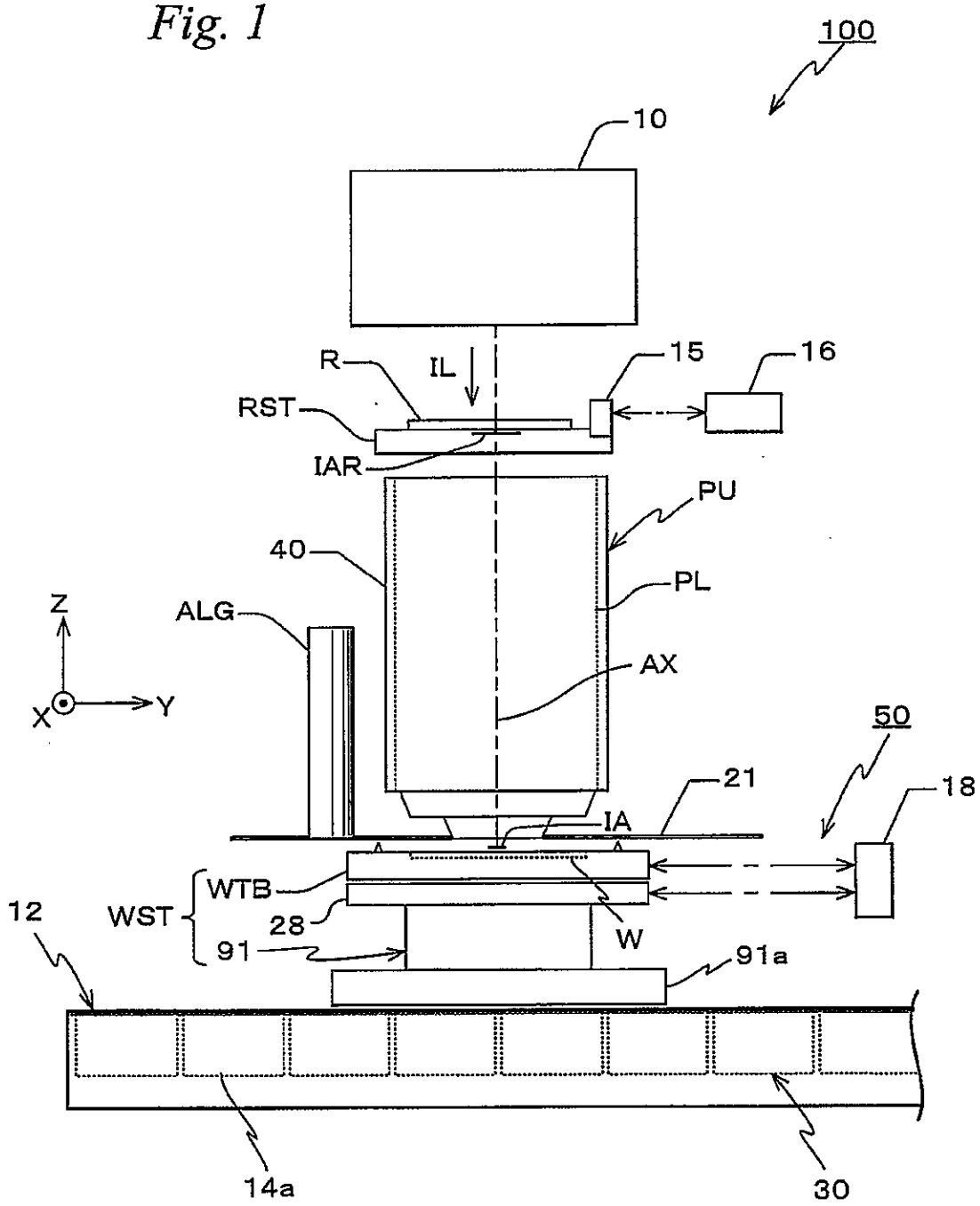

100
10
R
IL
15
16
RST
IAR
PU
40
PL
ALG
Z
X
Y
AX
50
21
18
IA
WTB
WST
28
91
W
12
91a
14a
30

Fig. 2

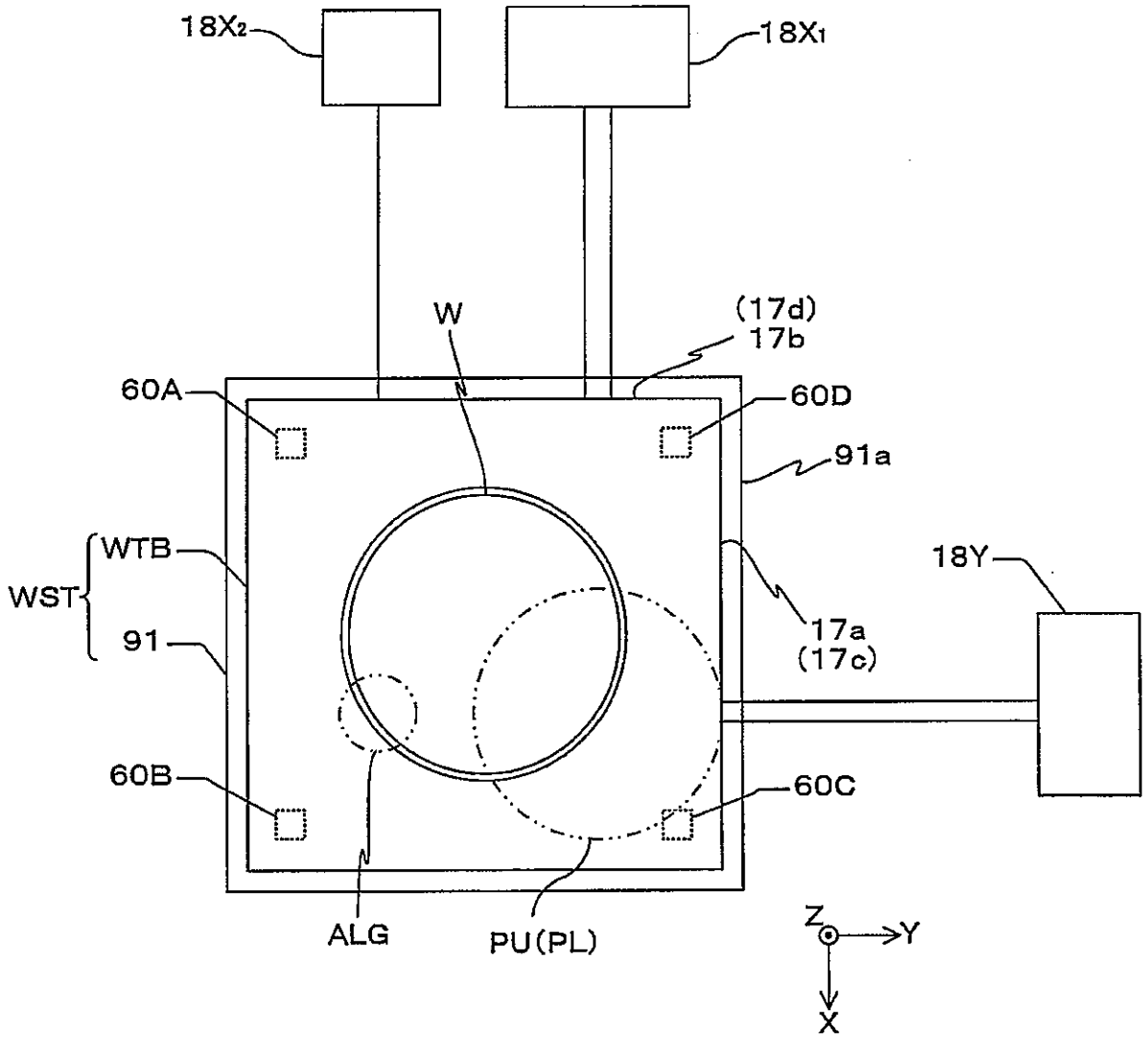

18X2
18X1
W
(17d)
17b
60A
60D
91a
WST
WTB
91
18Y
17a
(17c)
60B
60C
ALG
PU(PL)
Z
Y
X

Fig. 3

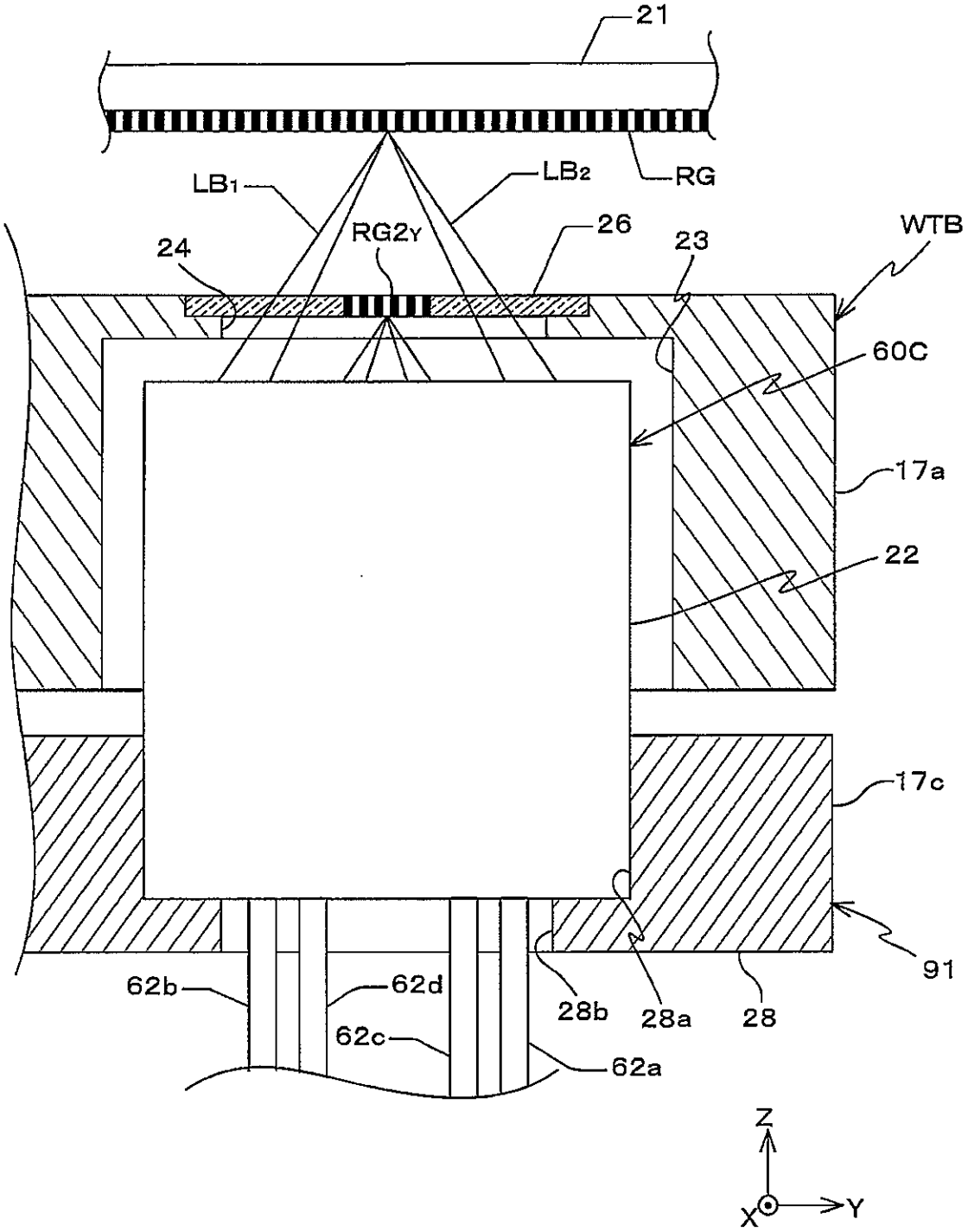

21
RG
LB1
LB2
RG2Y
26
23
24
WTB
60C
17a
22
17c
91
62b
62d
62c
62a
28b
28a
28
Z
X
Y

Fig. 4

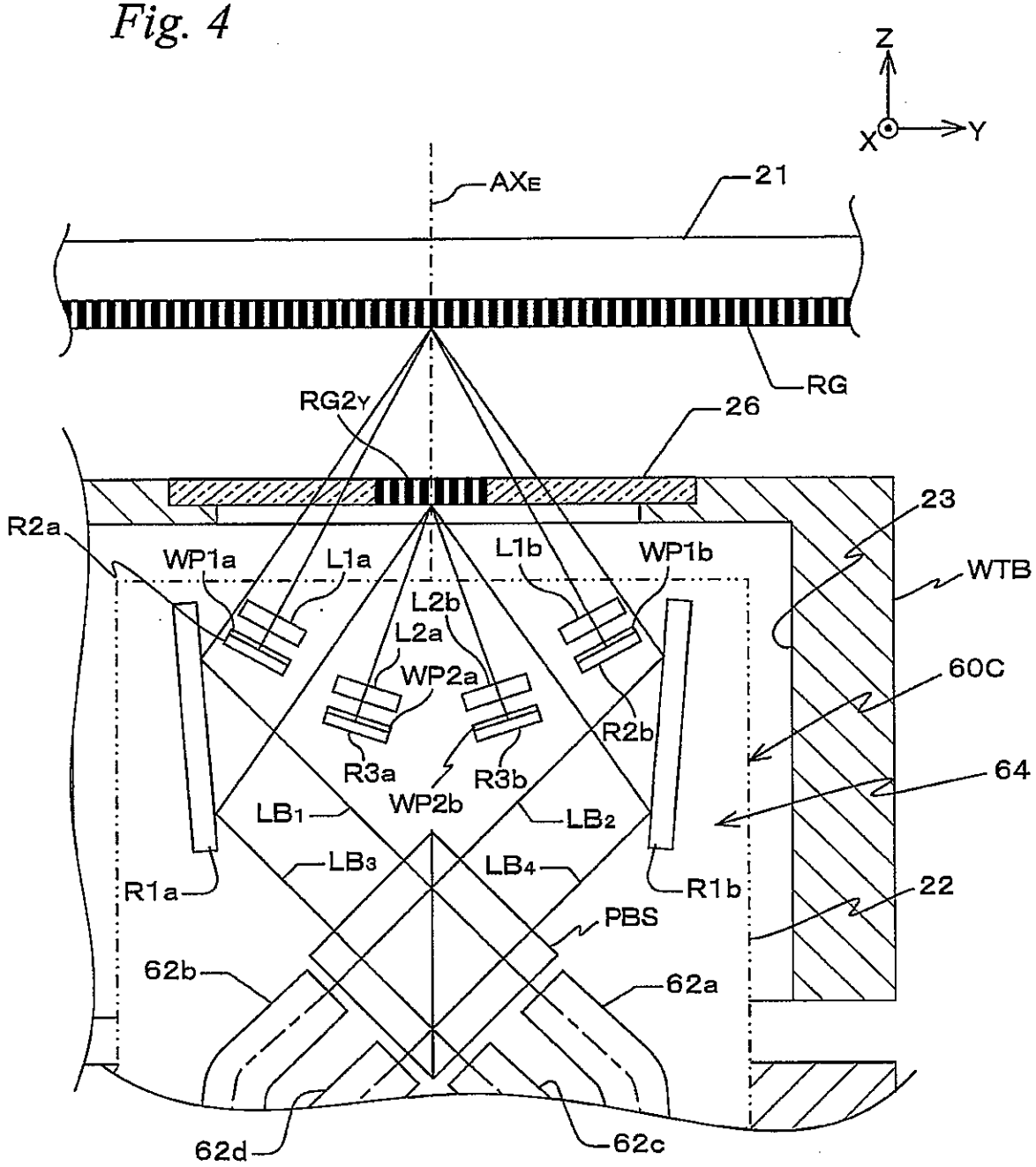
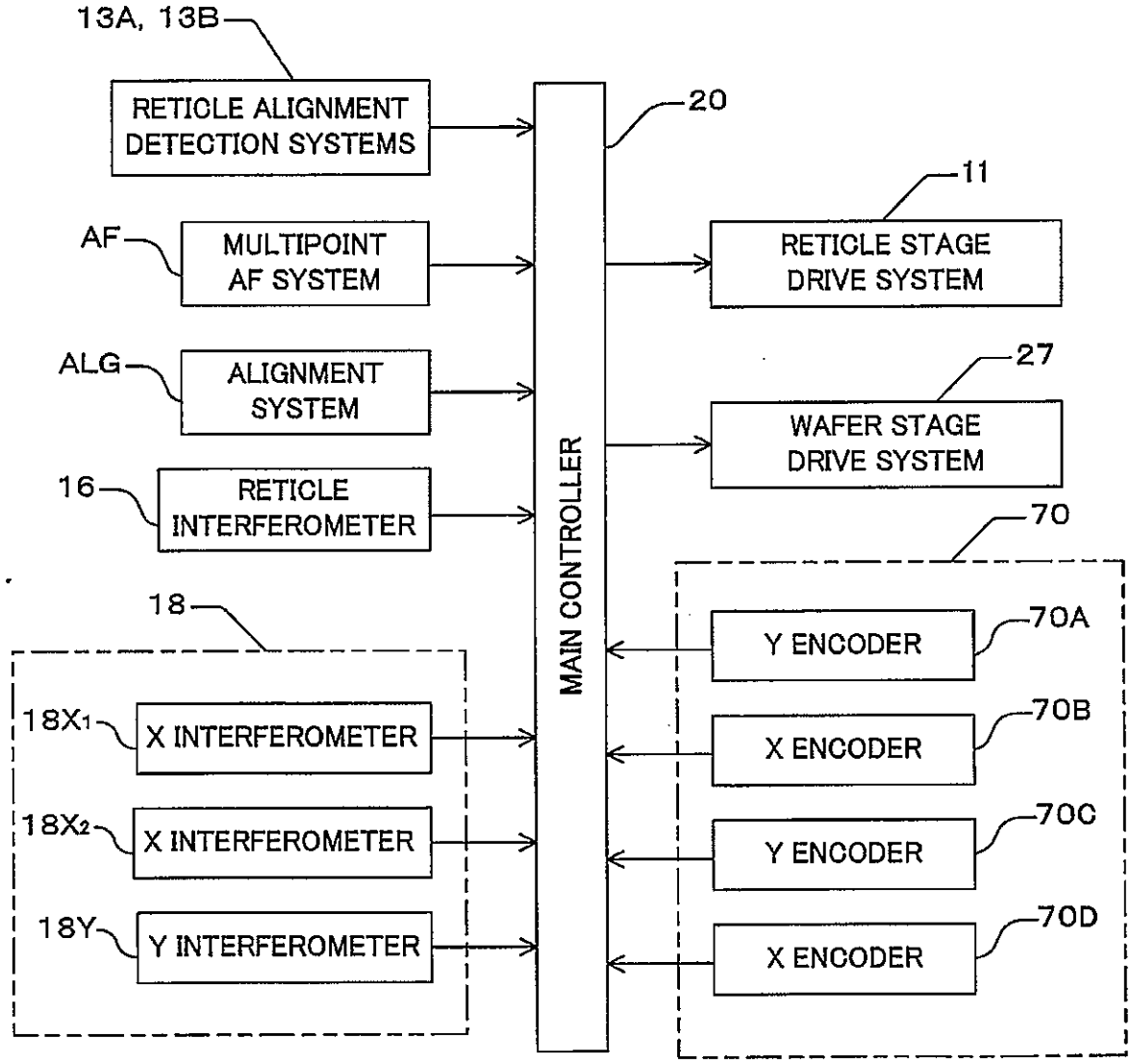

Z
X
Y
AXE
21
RG
RG2Y
26
23
WTB
60C
64
22
R2a
WP1a
L1a
L1b
WP1b
L2b
L2a
WP2a
R2b
R3a
R3b
WP2b
LB1
LB2
LB3
LB4
R1a
R1b
PBS
62b
62a
62d
62c

Fig. 5


13A, 13B
RETICLE ALIGNMENT DETECTION SYSTEMS
AF
MULTIPOINT AF SYSTEM
ALG
ALIGNMENT SYSTEM
16
RETICLE INTERFEROMETER
18
18X1
X INTERFEROMETER
18X2
X INTERFEROMETER
18Y
Y INTERFEROMETER
MAIN CONTROLLER
20
11
RETICLE STAGE DRIVE SYSTEM
27
WAFER STAGE DRIVE SYSTEM
70
Y ENCODER
70A
X ENCODER
70B
Y ENCODER
70C
X ENCODER
70D